Record Nr.	UNINA9910777418303321
Titolo	Plasma processing and processing science [[electronic resource] /] / Panel on Plasma Processing, Naval Studies Board, Commission on Physical Sciences, Mathematics, and Applications, National Research Council
Pubbl/distr/stampa	Washington, D.C., : National Academy Press, 1995
Descrizione fisica	1 online resource (45 p.)
Collana	NRL strategic series
Altri autori (Persone)	ChenFrancis F. <1929->
Disciplina	621.044
Soggetti	Plasma engineering Semiconductors - Etching Plasma etching
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Committee chair: Francis F. Chen. This work was performed under Department of Navy Contract N00014- 93-C-0089 issued by the Office of Naval Research under contract authority NR 201-124.
Nota di contenuto	""Plasma Processing and Processing Science""; ""Copyright""; ""Preface""; ""Contents""; ""Chapter 1 Introduction and Summary""; ""Chapter 2 Modeling and Simulation of Plasma Processing""; ""RESEARCH OPPORTUNITIES""; ""Requirements of the Microelectronics Fabrication Industry""; ""Multidimensional Models""; ""Plasma Chemistry""; ""Surface Chemistry""; ""Electromagnetics""; ""Current Status of Modeling and Simulation"; ""Particle-in-Cell Simulations""; ""Kinetic Models""; ""Fluid or Hydrodynamic Models""; ""Hybrid Models""; ""A ROLE FOR NRL""; ""Chapter 3 Semiconductor Processing"" ""RESEARCH OPPORTUNITIES"""A ROLE FOR NRL""; ""Development and Characterization of Precompetitive Materials and Processes"; ""Comparative Analysis and Characterization of Tools and Processes in Development"; ""Sensor Development for Control and Fingerprinting of Manufacturing Processes"; ""Chapter 4 Plasma Deposition and Polymerization""; ""RESEARCH OPPORTUNITIES""; ""Semiconductor Fabrication""; ""RESEARCH OPPORTUNITIES"; ""Semiconductor Fabrication"; ""Barrier Coatings"; ""Fibrous Materials"; ""Optical Coatings and Photonics"; ""Plasma Polymerization"; ""A ROLE FOR

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NRL""; ""Chapter 5 Ion Implantation and Surface Modification"" ""RESEARCH OPPORTUNITIES"""Introduction""; ""Plasma and Ion Beam Implantation Technology""; ""Ion Beam Implantation""; ""Plasma Source Ion Implantation""; ""Applications""; ""Implantation of Metals""; ""Implantation of Nonmetals""; ""A ROLE FOR NRL""; ""Chapter 6 Thermal Plasmas""; ""RESEARCH OPPORTUNITIES""; ""Introduction""; ""Plasma Spraying""; ""Plasma Chemical Vapor Deposition""; ""Plasma Waste Destruction""; ""Plasma Metallurgy""; ""Thermal Plasma Synthesis""; ""Plasma Consolidation""; ""A ROLE FOR NRL""; ""Thermal Plasma Waste Destruction""; ""Plasma Chemical Vapor Deposition"" ""Diamond Films""""Cubic Boron Nitride Films""; ""Carbon Nitride""; ""Chapter 7 Flat Panel Displays""; ""RESEARCH OPPORTUNITIES""; ""Introduction""; ""Passive Matrix Liquid Crystal Display""; ""Active Matrix Liquid Crystal Display""; ""Amorphous Silicon""; ""Polycrystalline Silicon""; ""Transfer Silicon""; ""Thin Film Electroluminescent Displays""; ""Digital Micromirror Devices""; ""Plasma Displays""; ""Field Emission Displays""; ""A ROLE FOR NRL""; ""Chapter 8 Low-Temperature Plasma Physics""; ""RESEARCH OPPORTUNITIES""; ""A ROLE FOR NRL""; ""Chapter 9 Conclusions and Recommendations"" ""RECOMMENDATION FOR A PROGRAM IN PLASMA PROCESSING AND PROCESSING SCIENCE"""CONCLUSIONS BASED ON NRL'S PRESENT RESEARCH CAPABILITIES""